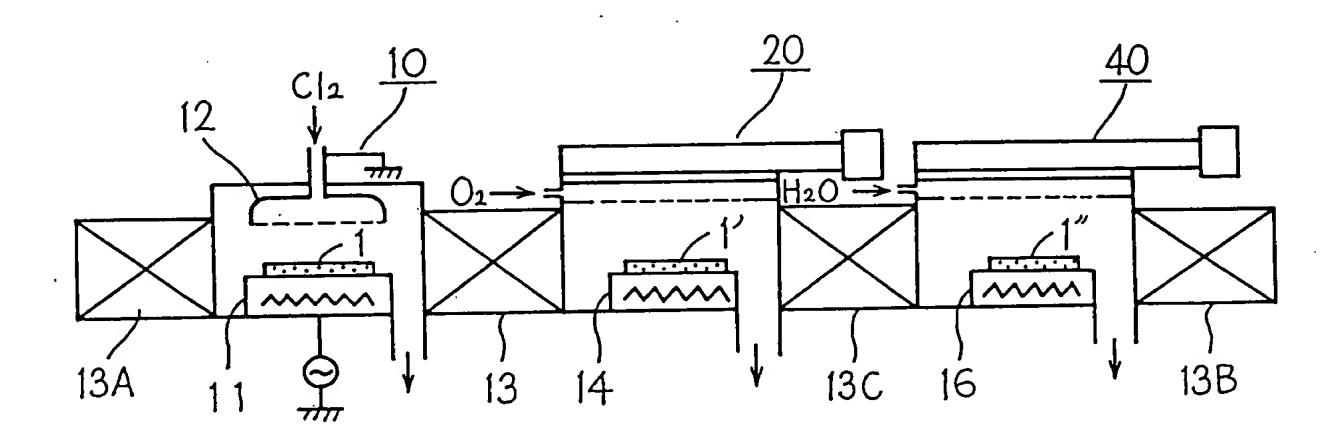
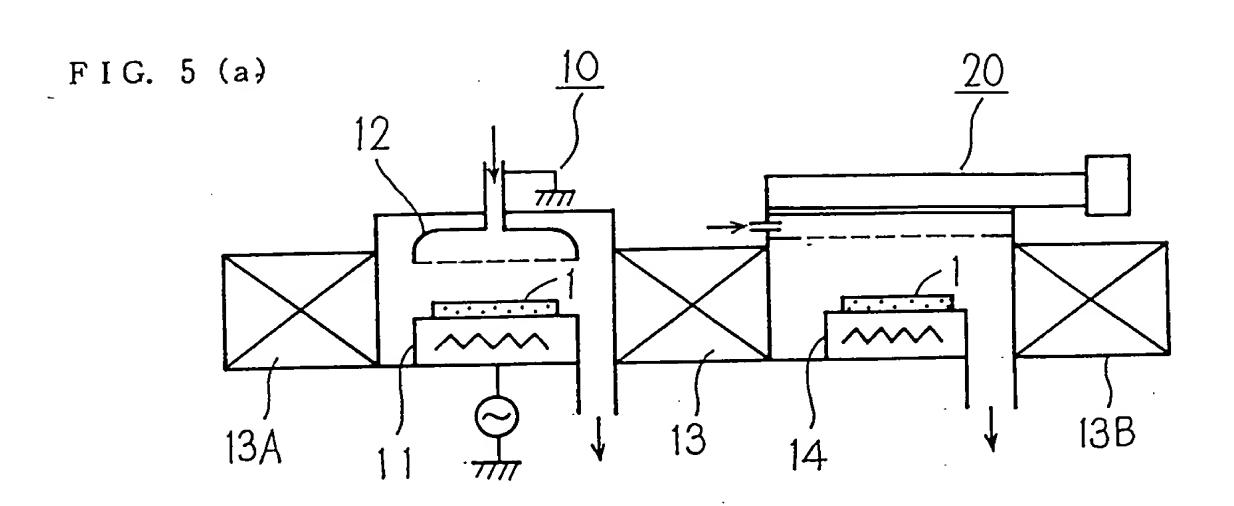
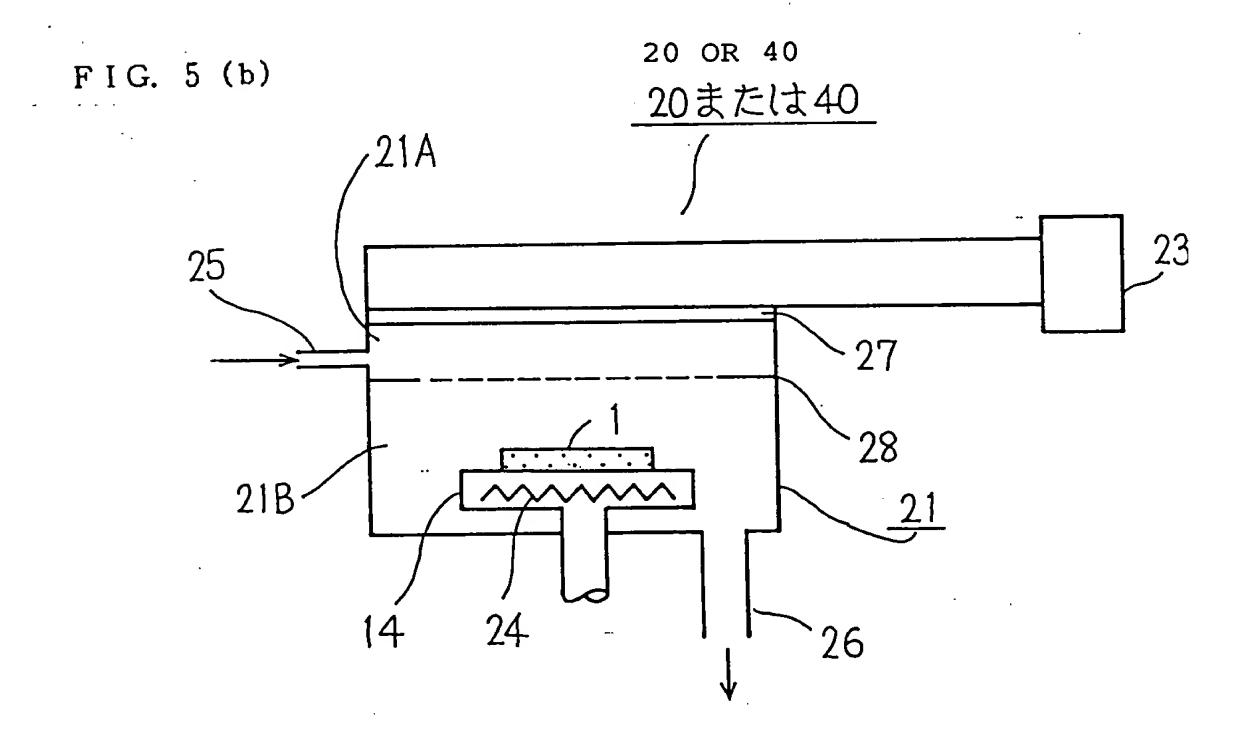


FIG. 4







F I G. 6

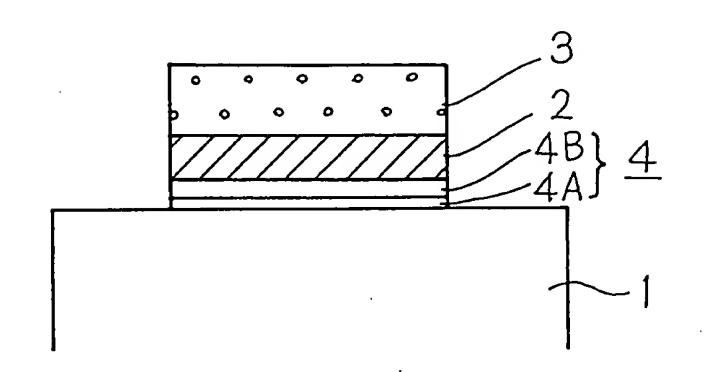


FIG. 7

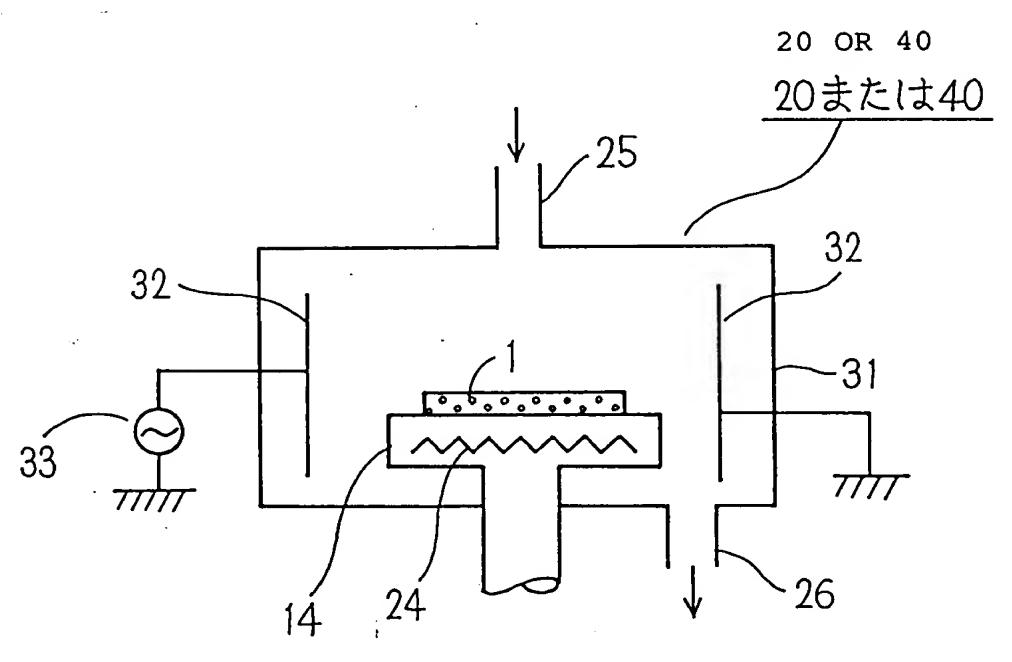
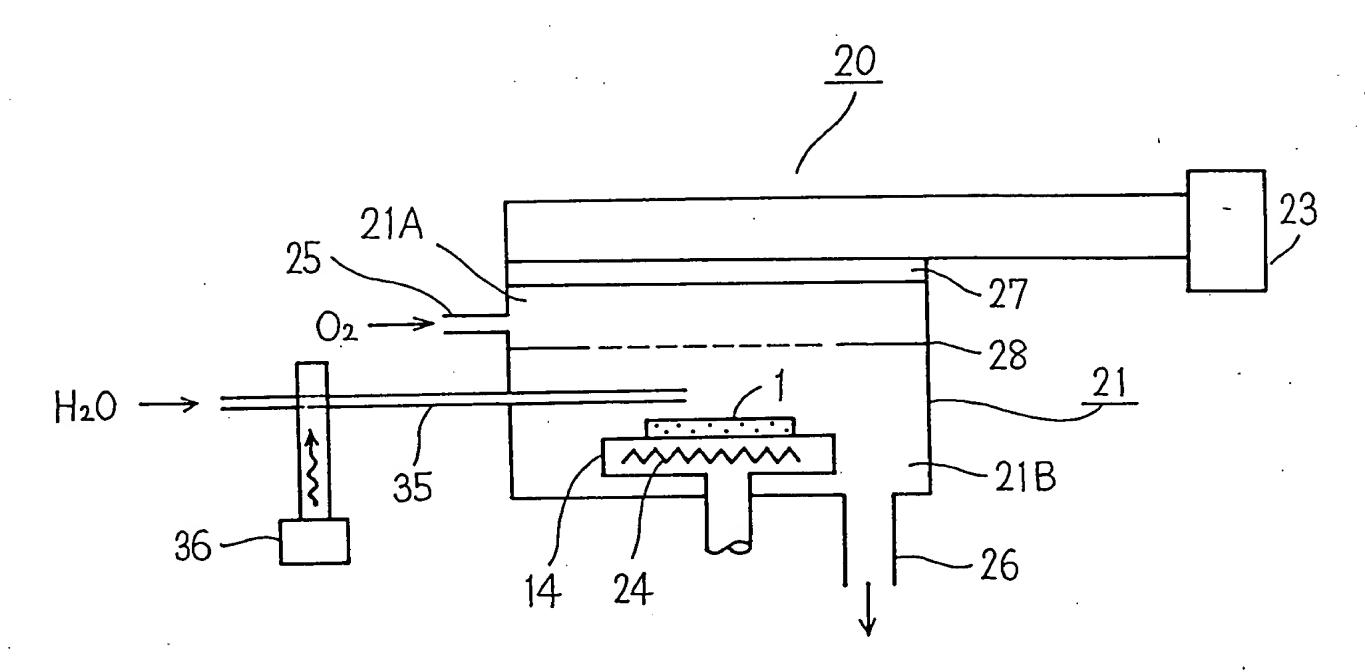


FIG. 8



F I G. 9

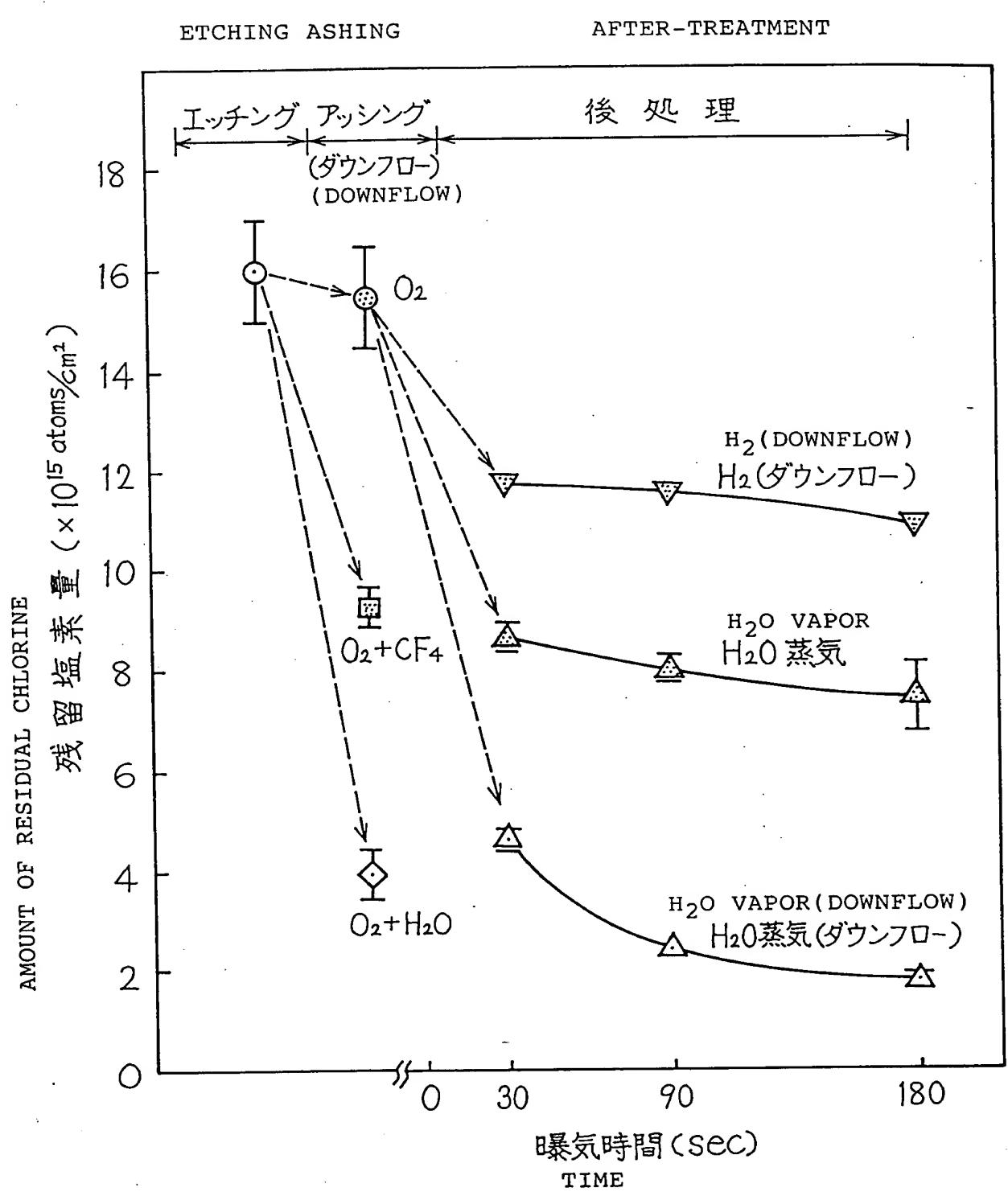


TABLE OF REFERENCE NUMERALS 参照符号・事項の一覧表

1, 1', 1"··基板, SUBSTRATE

2 · · · アルミニウム膜, ALUMINUM FILM

 $3 \cdot \cdot \cdot \neg \neg \neg \neg \neg$ MASK

4 · · · バリヤメタル, BARRIER METAL

10···RIE 装置, RIE APPARATUS

11, 14· · · ステージ, STAGE

12, 16, 32···電極, ELECTRODE

13, 13A, 13B, 13C · · ・ロードロック室, LOAD LOCK CHAMBER

20 · · · アッシング装置, ASHING APPARATUS

21, 31 · · ・ チャンバ, CHAMBER

21A ・・・プラズマ発生室, PLASMA GENERATING CHAMBER

21B · · · アッシング室, ASHING CHAMBER

23, 36···マイクロ波発生源, MICROWAVE GENERATION SOURCE

 $24 \cdot \cdot \cdot \vdash - 9$, HEATER

25, 35···ガス導入管, GAS INTRODUCTION PIPE

26···排気管, EXHAUST PIPE

28・・・シャワーヘッド, SHOWER HEAD

33···高周波電源, HIGH FREQUENCY POWER SUPPLY

40···後処理装置 AFTER-TREATMENT APPARATUS